

attached directly to a facet of a wafer handling chamber. Furthermore, Morioka et al. ('434) discloses inspection systems, which are very different from metrology tools.


It is also respectfully submitted that none of the references of Morioka et al. (U.S. Patent No. 5,274,434), Morioka et al. (U.S. Patent No. 5,463,459), Yamamoto et al. (U.S. Patent No. 5,623,340), and Levy (U.S. Patent No. 5,465,154), taken alone or in combination, teach or suggest the inventions of claims 59 and 65 as described above. Therefore, it is respectfully submitted that independent claims 59 and 65 are patentably distinct from the cited references of Morioka et al. (U.S. Patent No. 5,274,434) taken with Morioka et al. (U.S. Patent No. 5,463,459) and Yamamoto et al. (U.S. Patent No. 5,623,340), and also with Levy (U.S. Patent No. 5,465,154). It is also submitted that dependent claims 60-64 and 66 are patentably distinct from the cited references for at least the same reasons as stated above.

SUMMARY

It is respectfully submitted that all pending claims are allowable and that this case is now in condition for allowance. Should the Examiner believe that a telephone conference would expedite the prosecution of this application, the undersigned can be reached at the telephone number set out below.

If any fees are due in connection with the filing of this Amendment, the Commissioner is authorized to deduct such fees from the undersigned's Deposit Account No. 500388 (Order No. KLA1P001C1). A duplicate copy of the transmittal sheet for this amendment is enclosed for this purpose.

Respectfully submitted,
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